



**RETURN BIDS TO:**

**RETOURNER LES SOUMISSIONS À:**

Bid Receiving - PWGSC / Réception des soumissions -  
TPSGC

11 Laurier St./ 11 rue, Laurier

Place du Portage, Phase III

Core 0B2 / Noyau 0B2

Gatineau, Québec K1A 0S5

Bid Fax: (819) 997-9776

**SOLICITATION AMENDMENT  
MODIFICATION DE L'INVITATION**

The referenced document is hereby revised; unless otherwise  
indicated, all other terms and conditions of the Solicitation  
remain the same.

Ce document est par la présente révisé; sauf indication contraire,  
les modalités de l'invitation demeurent les mêmes.

**Comments - Commentaires**

**Vendor/Firm Name and Address**

Raison sociale et adresse du  
fournisseur/de l'entrepreneur

**Issuing Office - Bureau de distribution**

Scientific, Medical and Photographic Division /  
Division de l'équipement scientifique, des produits  
photographiques et pharmaceutiques  
L'Esplanade Laurier  
140 O'Connor Street,  
East Tower, 7th Floor  
Ottawa  
Ontario  
K1A 0S5

|   |   |
|---|---|
| <b>Title - Sujet</b><br>High-Vacuum Carbon Coater   |   |
| <b>Solicitation No. - N° de l'invitation</b><br>23240-200625/A  | <b>Amendment No. - N° modif.</b><br>001     |
| <b>Client Reference No. - N° de référence du client</b><br>23240-200625   | <b>Date</b><br>2020-07-21                   |
| <b>GETS Reference No. - N° de référence de SEAG</b><br>PW-\$\$PV-899-78891  |   |
| <b>File No. - N° de dossier</b><br>pv899.23240-200625   | <b>CCC No./N° CCC - FMS No./N° VME</b>      |
| <b>Solicitation Closes - L'invitation prend fin</b><br><b>at - à 02:00 PM</b><br><b>on - le 2020-08-07</b>  |   |
| <b>Time Zone</b><br>Fuseau horaire<br>Eastern Daylight Saving<br>Time EDT   |   |
| <b>F.O.B. - F.A.B.</b> Specified Herein - Précisé dans les présentes<br><b>Plant-Usine:</b> <input type="checkbox"/> <b>Destination:</b> <input type="checkbox"/> <b>Other-Autre:</b> <input checked="" type="checkbox"/> |   |
| <b>Address Enquiries to: - Adresser toutes questions à:</b><br>Van Den Hanenberg, Stephen   | <b>Buyer Id - Id de l'acheteur</b><br>pv899 |
| <b>Telephone No. - N° de téléphone</b><br>(343) 540-8371 ( )  | <b>FAX No. - N° de FAX</b><br>( ) -         |
| <b>Destination - of Goods, Services, and Construction:</b><br><b>Destination - des biens, services et construction:</b>   |   |

Instructions: See Herein

Instructions: Voir aux présentes

|  |  |
|--|--|
| <b>Delivery Required - Livraison exigée</b>  | <b>Delivery Offered - Livraison proposée</b> |
| <b>Vendor/Firm Name and Address</b><br><b>Raison sociale et adresse du fournisseur/de l'entrepreneur</b>   |  |
| <b>Telephone No. - N° de téléphone</b><br><b>Facsimile No. - N° de télécopieur</b>   |  |
| <b>Name and title of person authorized to sign on behalf of Vendor/Firm</b><br><b>(type or print)</b><br><b>Nom et titre de la personne autorisée à signer au nom du fournisseur/</b><br><b>de l'entrepreneur (taper ou écrire en caractères d'imprimerie)</b> |  |
| <b>Signature</b>   | <b>Date</b>                                  |

---

Amendment 001 has been raised to provide answers to questions from industry.

### **Questions and Answers**

- Q1.** Based on applications mentioned, we assume the typical usage of two sources are options. That is one source being replaced by the other depending on application, and not a hybrid system that both sources should be simultaneously in the deposition chamber. Could you confirm please?
- A1.** As stated in the Coating Sources section of the Mandatory Specifications, the two sources need to be integrated in the system and be both available without hardware modification for alternate use (distinct coating sessions). Consequently they do not need to be simultaneous in the deposition chamber.
- Q2.** The specifications give strict dimensions of 100 cm width x 70 cm depth x 80 cm height. Is there an enclosed space that the equipment should enter? If not, then by maintaining the same volume is there room, for 10% variation in those dimensions? If it is installed in an enclosed space, when exchanging sources (assuming that is the case) would there be more room above the 80 cm height limitation to execute the exchange?
- A2.** We have a specific area where the instrument will be installed in one of our electron microscopy laboratory on a standing-height lab bench (91.44 cm) having a depth of 73.6 cm. Considering also the existing instruments, accessories, and working space on that table, the maximum width (100 cm) and depth (70 cm) dimensions of the unit stated are strict. Nevertheless in terms of height, having an excess not exceeding 10% relative (8 cm) to allow exchange could be acceptable, but definitely not more as reachable access is necessary.
- Q3.** What is the diameter of required sputtering target? Could you specify the required thickness of the platinum target?
- A3.** There is no specific requirement for the diameter of the sputtering target except that it is compatible with the instrument provided. No minimum target thickness is specified in the mandatory requirements.
- Q4.** In item 6, requirement specified motorized rotary and planetary motion. In item 7, only requirement specifies 90 mm height adjustment. However, item 15 is not clear. Does it require that All possible motions (axial, rotary /planetary and tilt motions) be controlled automatically DURING the SAME PROCESS run, without exposing the process to air or stoppage? Typically, our axial rotary /planetary motions could be coupled and controlled simultaneously, if required; however, adding the tilting is not computer controlled. Is this acceptable?
- A4.** Considering the multiple-user environment, the importance of reproducibility and quality of coating coverage, we do require, as stated in the mandatory requirements, programmable routines that control all stage movements including tilt.
- Q5.** In automated process control, (1) Is PID control of operation pressure a required variable parameter during sputtering operation? If not, (2) is gas flow control rate a variable control parameter?
- A5.** There are no specific requirements in automated process control regarding PID control or gas flow control as variable parameters during sputtering operation.

Solicitation No. - N° de l'invitation  
23240-200615/A  
Client Ref. No. - N° de réf. du client  
23240-200615

Amd. No. - N° de la modif.  
001  
File No. - N° du dossier  
pv899.23240-200615

Buyer ID - Id de l'acheteur  
pv899  
CCC No./N° CCC - FMS No./N° VME

---

**Q6.** Does user require real time data logging and storage during the process (for future recall and verification) or a simple real time data display, and recipe run?

**A6.** Real-time data logging and storage are not part of the mandatory requirements.

**ALL OTHER TERMS AND CONDITIONS OF THE SOLICITATION  
REMAIN THE SAME**